Pursuant to MPEP §715.07 supporting documentary evidence as well as an eyewitness account by corroborating witness Harki Singh are provided to show reduction to practice prior to 6/20/2003. The supporting documentary evidence complying with MPEP §715.07 includes photocopies of: (C) photographs, (D) notebook entries, (F) statement by witness of audio/visual presentation, and (H) a witnessed invention disclosure document.

The declarations and supporting evidence clearly explain how the inventors demonstrated to the satisfaction of others skilled in the field that the inventors had recognized a problem (micromasking) and had reduced to actual practice a novel method of solving the problem (the "sputter etch" solution) and had timely submitted an invention disclosure to a law firm for preparation and filing of a corresponding patent application (namely, the subject application), all this occurring before the 6/20/2003 filing date of the Doshita reference. As such the inventors have demonstrated a sufficient basis for antedating the effective date of the Doshita reference.

CONCLUSION

It is believed that all outstanding rejections are overcome by removal of the Doshita reference. Additionally it is submitted that attached Exhibit C demonstrates how difficult it is to determine the structure of micromasking residue because a chemical analysis alone does not indicate what is going on. Real world residue is contaminated with numerous compounds due to the complexity of plasma etching. The inventors had an a priori insight as to what was going on so that they could use the Exhibit C results to confirm their theories. Additionally, the successful experimental results (wafer number 22) confirmed their theories and constituted actual reduction to practice. Given that Doshita is removed, it is respectfully submitted that no rejection is outstanding and it is respectfully requested that allowable subject matter be again indicated as it was in earlier Office actions. Should any other action be

LAW OFFICES OF MacPherson, Kwok, Chen & Heid LLP 2035 Chewny Place Saite 400 Sm Jose, CA 95110 contemplated by the Examiner, it is respectfully requested that he contact the undersigned at (408) 392-9250 to discuss the application.

The Commissioner is authorized to charge any underpayment or credit any overpayment to Deposit Account No. 50-2257 for any matter in connection with this response, including any fee for extension of time and/or fee for consideration of the submissions, which may be required.

CERTIFICATE OF EFS-WEB TRANSMISSION

Certificate of Transmission: I hereby certify that this correspondence is being transmitted to the United States Patent and Trademark Office (USPTO) via the USPTO's EFS-Web electronic filing system

June 3, 2008 (Date).

Typed or printed name of person signing this certificate:

Gideon Gimlan

Signature:

MacPherson Kwok Chen & Heid LLP 2033 Gateway Place, Suite # 400 San Jose, CA 95110

Tel: (408) 392-9250

Respectfully submitted,

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Gideon Gimlan Attorney for Applicants Reg. No. 31,955

LAW OFFICES OF MacPherson, Kwok, Chen & Held LLP

2033 Gateway Place Seite 400 San Jose, CA 95110 Telephone: (406)-392-9520 Passimile: (406)-392-9202